

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**SECOND SUPPLEMENTAL INFORMATION
DISCLOSURE STATEMENT BY APPLICANT**

Atty. Docket No.
UBAT1510



The PTO did not receive the following listed item(s) a check for \$180.

Applicant Gregory R. Hanson et al.	
Application Number 10/649,251	Filed August 26, 2003
For Spatial Heterodyne Interferometry for Transmission (SHIFT) Measurements	
Group Art Unit 2877	Examiner Connolly, Patrick J

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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I hereby certify that this correspondence is being deposited with the U.S. Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on Aug 24, 2005.

John J. Bruckner

Applicants respectfully request, pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, that the art listed on the attached PTO-1449 form be considered and cited in the examination of the above-identified application. A copy of the art is enclosed for the convenience of the Examiner. Furthermore, pursuant to 37 C.F.R. §§ 1.97(g) and (h), no representation is made that a search has been made or that this art is material to patentability of the present application. Copies of the non-US patent references are enclosed for the convenience of the Examiner.

This Information Disclosure Statement is being filed after mailing of a First Office Action. Applicant hereby requests consideration of this Information Disclosure Statement pursuant to 37 C.F.R. § 1.97(c)(2). A check in the amount of \$180 representing the fee set forth in 37 CFR § 1.17(p) is enclosed.

While Applicants believe no (further) fees are due, if any (further) fees are due, the Commissioner is hereby authorized to charge any fees or credit any overpayments to Deposit Account No. 50-3204 of John Bruckner PC.

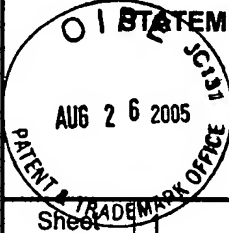
Dated: Aug 24, '05

5708 Back Bay Lane
Austin, TX 78739
Tel. (512) 394-0118
Fax. (512) 394-0119

Respectfully submitted,
John Bruckner PC

Attorneys for Applicant

John J. Bruckner
Reg. No. 35,816

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		First Named Inventor	Gregory R. Hanson
		Group Art Unit	2877
		Examiner Name	Connolly, Patrick J
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U.S. PATENT DOCUMENTS

Examiner Initials	Cite No.	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		Number	Kind Code (if known)		
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Examiner Initials	Cite No.	FOREIGN PATENT DOCUMENTS			Publication Date MM-DD-YYYY (Number 43)	Name of Patentee or Applicant of Cited Document
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		JP	06282213		07/10/1994	Citizen Watch Co. Ltd.
Examiner Signature					Date Considered	

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				Examiner Name	Connolly, Patrick J	
Sheet	1	of	2	Attorney Docket Number	UBAT1510	
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Examiner Signature				Date Considered	